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IN ELECTRONICS
MANUFACTURING

Five deep learning recipes for the mask making industry

Ajay Baranwal et al (CDLe)
Noriaki Nakayamada et al (NuFlare)
Mikael Wahlsten et al (Mycronic)
Aki Fujimura et al (D2S)

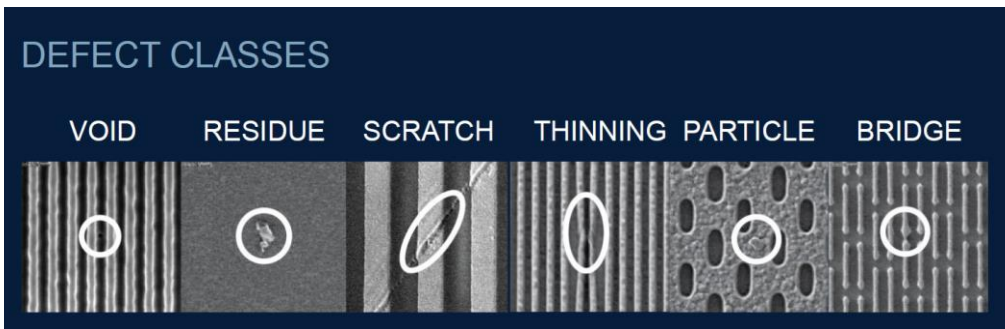
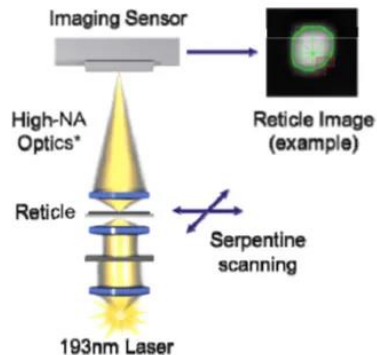
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D2S

DL can solve many mask industry problems



Mask inspection

Automatic defect categorization

Lithography hotspot detection

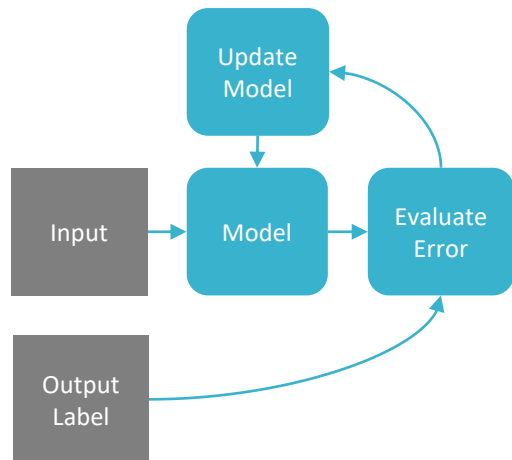
Fault detection and classification

Anomalous data synthesis

Many DL techniques are used at CDLe

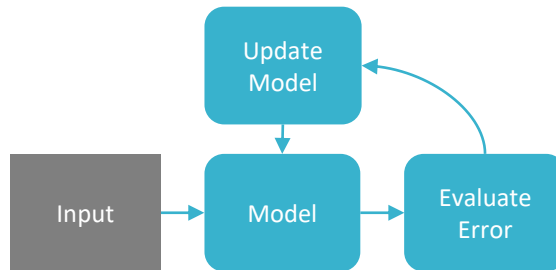
10 successful projects in past year

(Labeled data)



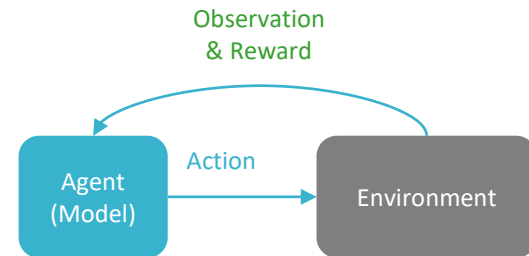
Supervised learning

(Unlabeled data)



Unsupervised learning

("Games")



Reinforcement learning



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Recipe #1: Mask rule error automatic categorization

Recommendation engines use deep learning

DL technique used: autoencoding (unsupervised DL)

amazon

Customers Who Bought This Item Also Bought



Oliver Twist (Dover Thrift Editions)
> Charles Dickens
★★★★☆ (213)
Paperback
\$3.50



David Copperfield (Dover Thrift Editions)
> Charles Dickens
★★★★☆ (196)
Paperback
\$5.00



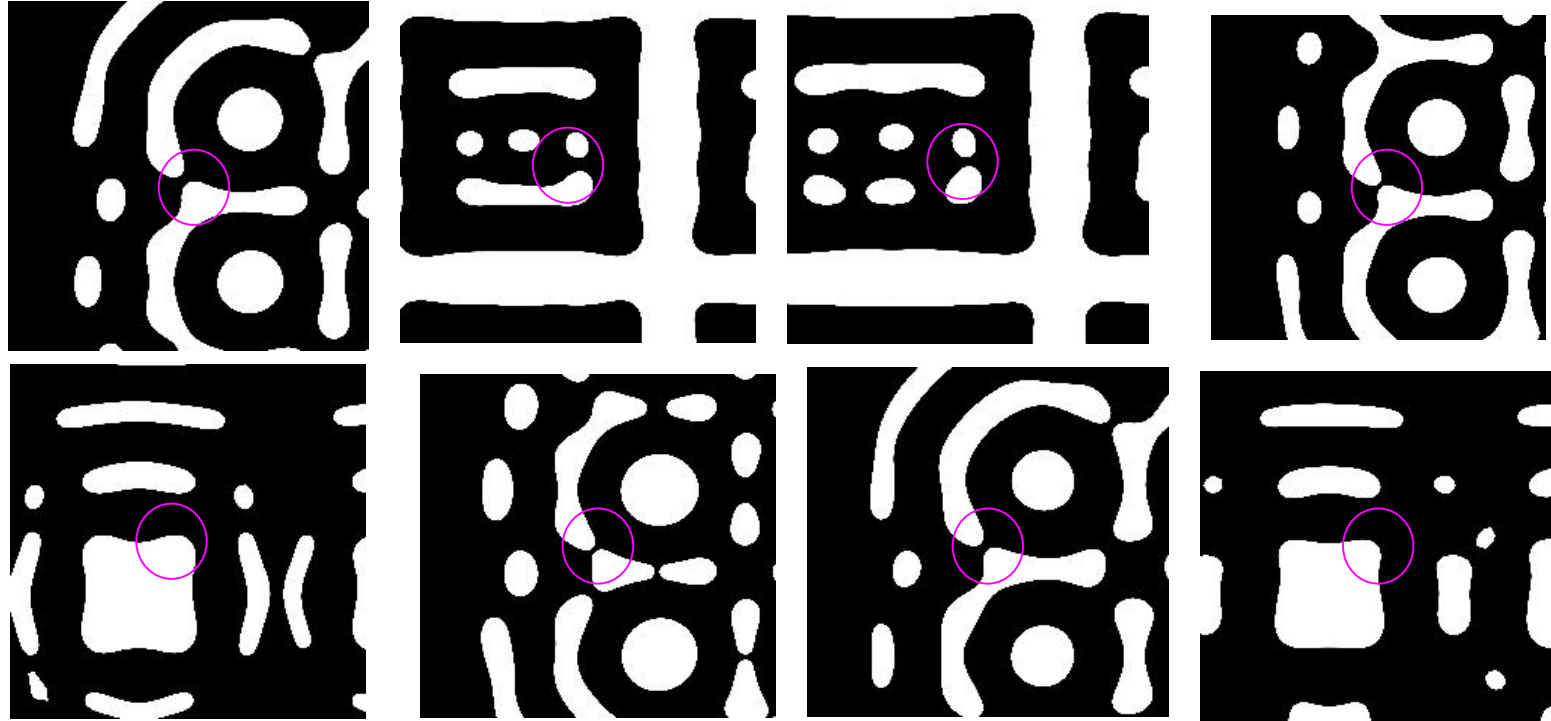
JANE EYRE
> Charlotte Bronte
★★★★☆ (1,045)
Paperback
\$2.99

NETFLIX



Mask rule check can generate thousands of errors

Best to report similar errors together

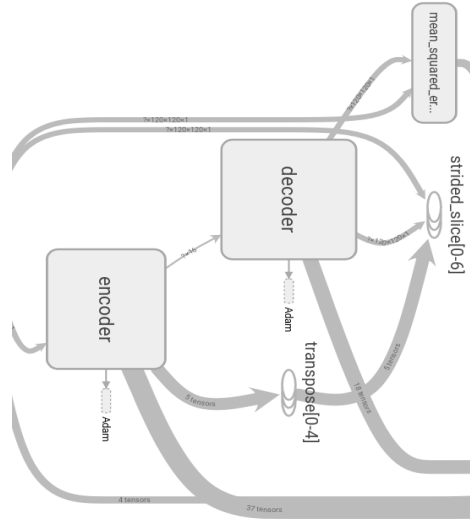


Unsupervised deep autoencoder captures similarity

After training, encoding abstracts out similar features



**Mask
image clip**



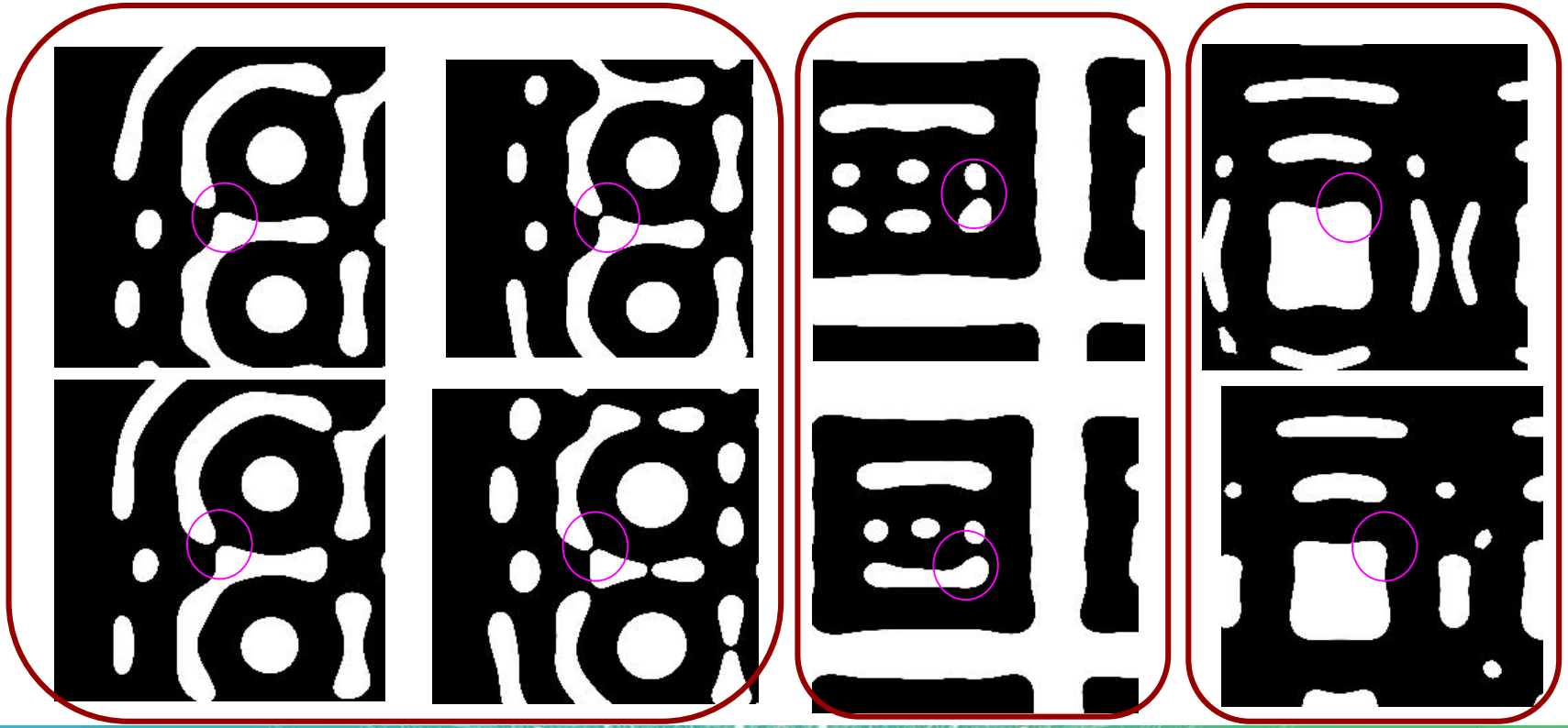
Autoencoder



5.8539410e+01,
2.1572763e+02,
1.4674566e+02,
6.1346753e+01,
...

**Series of numbers
(Also called encoding)**

Mask rule check groups similar errors together automatically





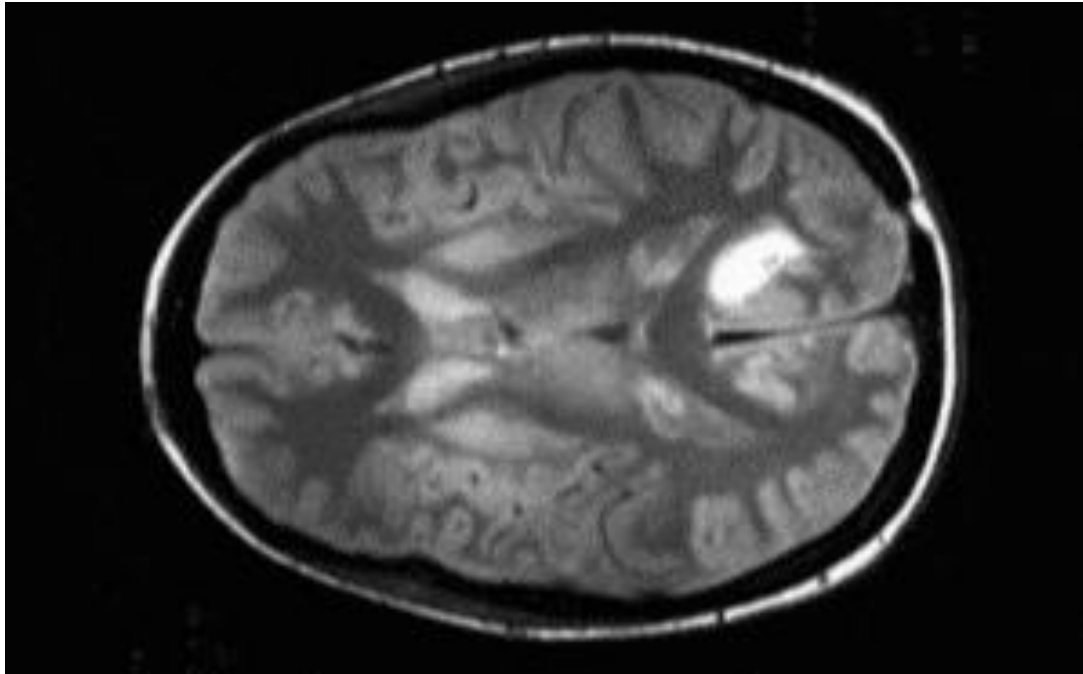
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Recipe #2: Fast mask design construction

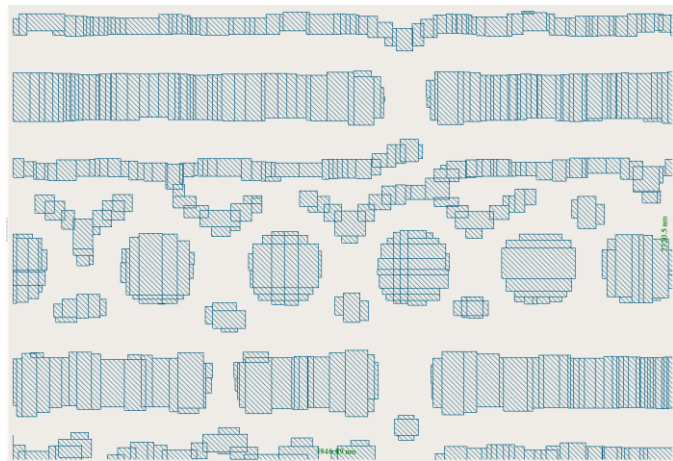
Medical diagnosis uses deep learning

DL technique used: U-net architecture (supervised learning)

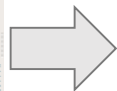


Faster but less accurate simulation is useful for evaluation

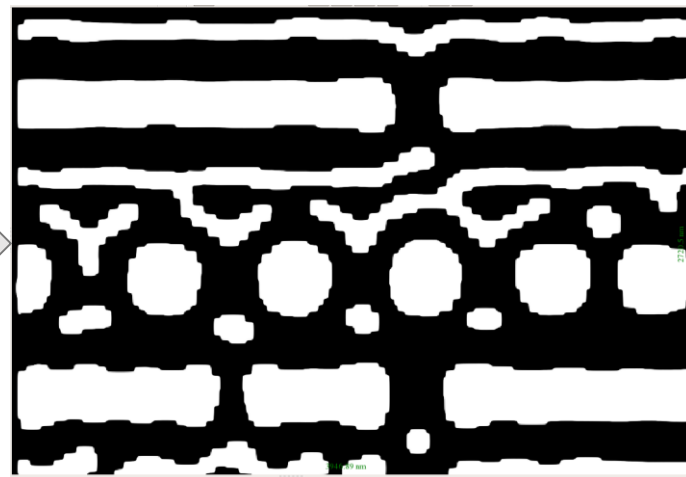
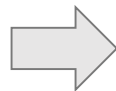
Quickly estimate downstream impact



Overlapping shots list

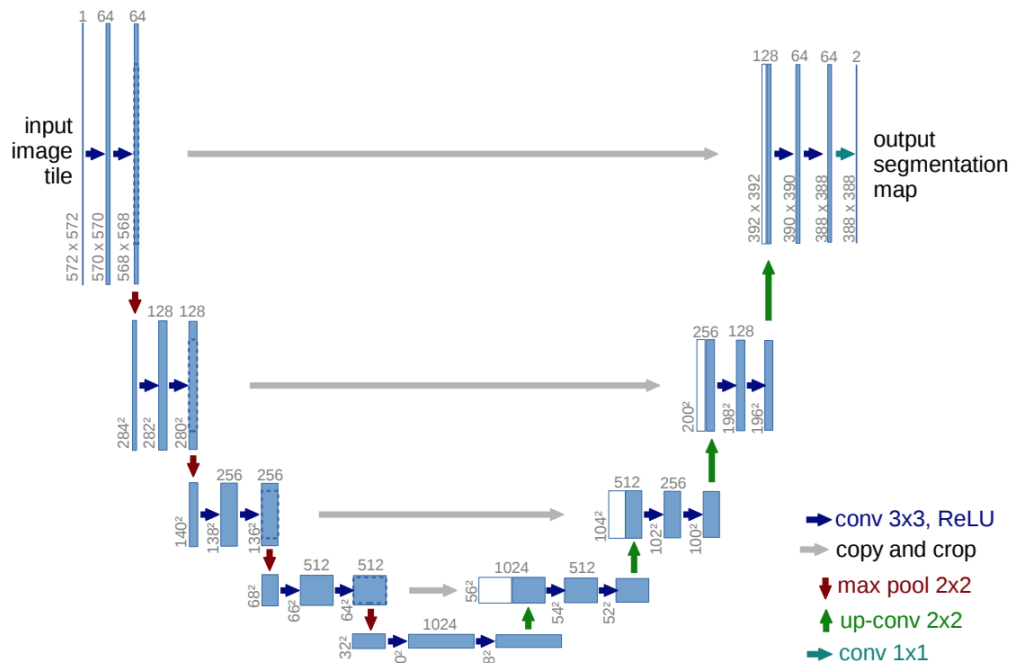


TrueModel^(R)
Simulation



Simulated dose map

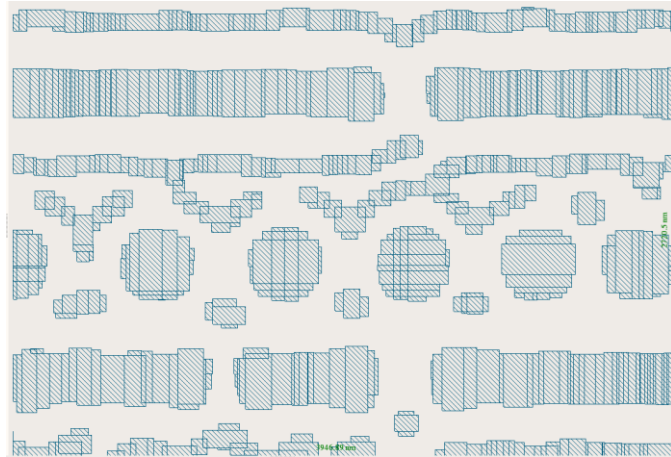
U-Net architecture translates images using pixel values



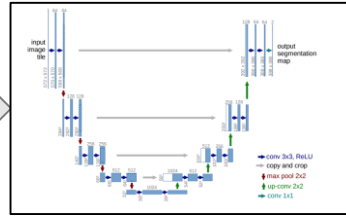
We customized architecture and loss function

DL can construct mask shapes from shots faster

Current implementation reduces run time by 2.5x



Overlapping shots list



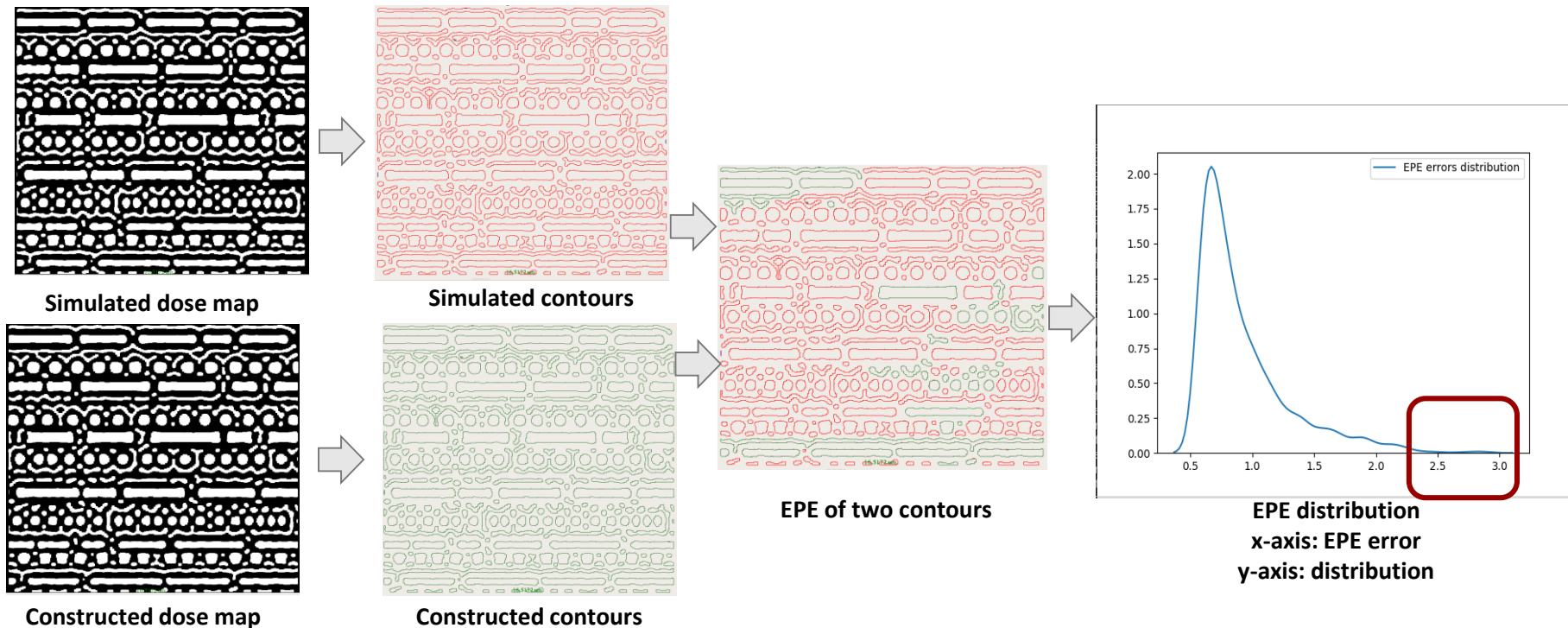
DL



Constructed dosemap

Max EPE error is below 3 nm even with overlapping shots

Not to replace simulation but useful for evaluation function



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Recipe #3: PCB component pick-and-place (PnP) error classification

Amazon Go automatic checkout uses deep learning

DL technique used: object classification, others (supervised DL)

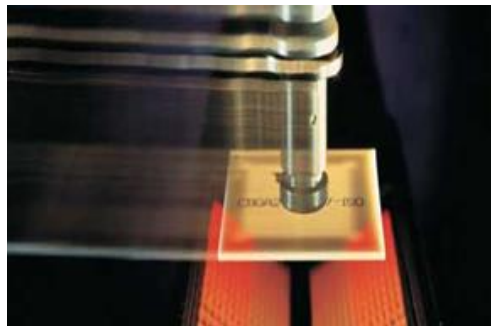


Incorrectly picked components need to be identified

Monitored using images of picked components



**Magazine
with components**



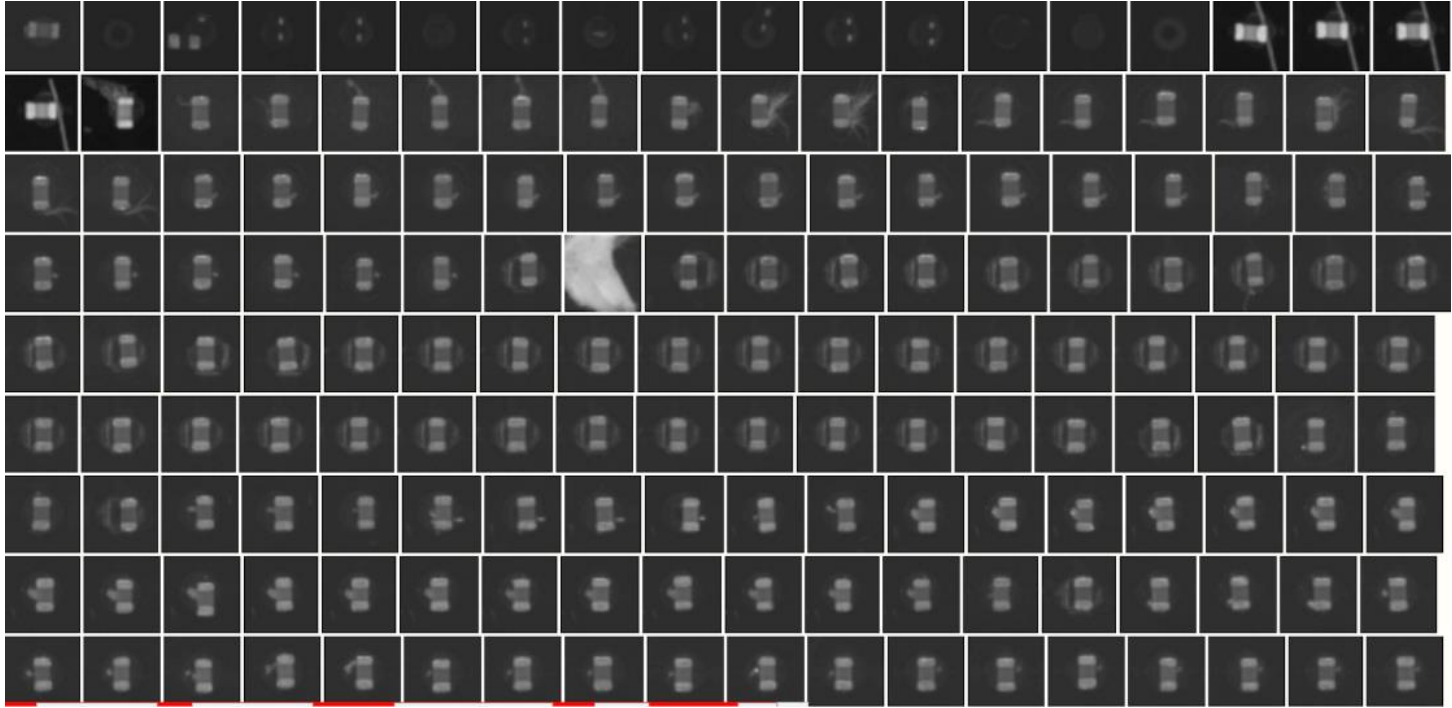
**Robot arm picked
a component
(Image taken)**



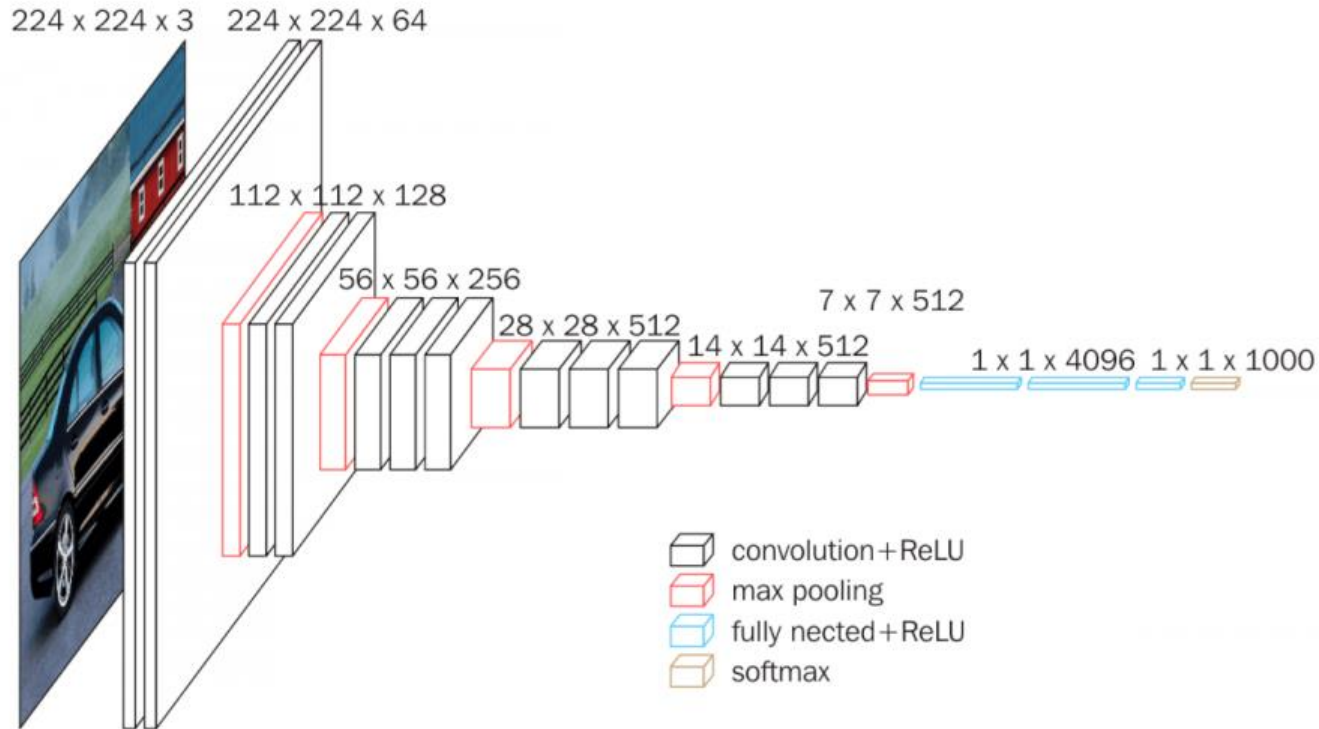
**Component
Mounted on PCB**

This problem is difficult

Classical computer vision is not sufficient



Object classification uses deep CNN



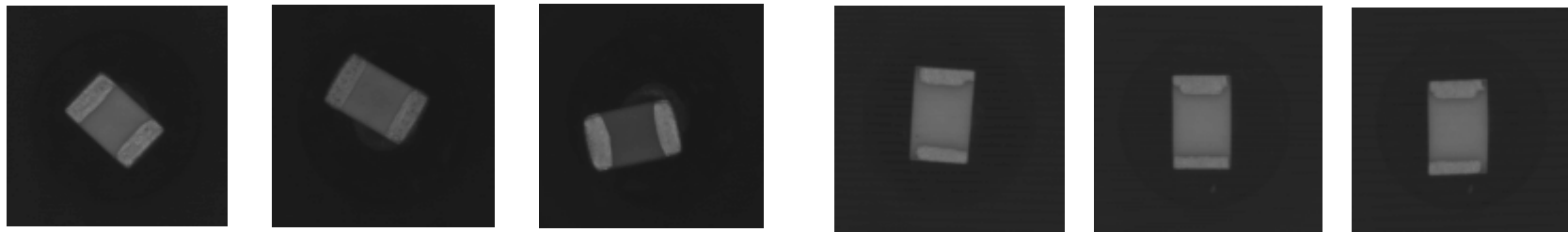
CNN based classifier was used to identify “Bad” PnP

Accuracy 99.76%, even on different machines



Bad-”Billboarded”

Bad-”Tombstone”



Bad - “Wrong pick angle”

OK

A background graphic featuring a complex network of white dots connected by thin white lines, resembling a neural network or data flow diagram. The dots are of varying sizes and are distributed across a green-to-blue gradient background. A large, semi-transparent green circle is centered in the upper half of the image, containing the text 'CENTER FOR DEEP LEARNING IN ELECTRONICS MANUFACTURING'.

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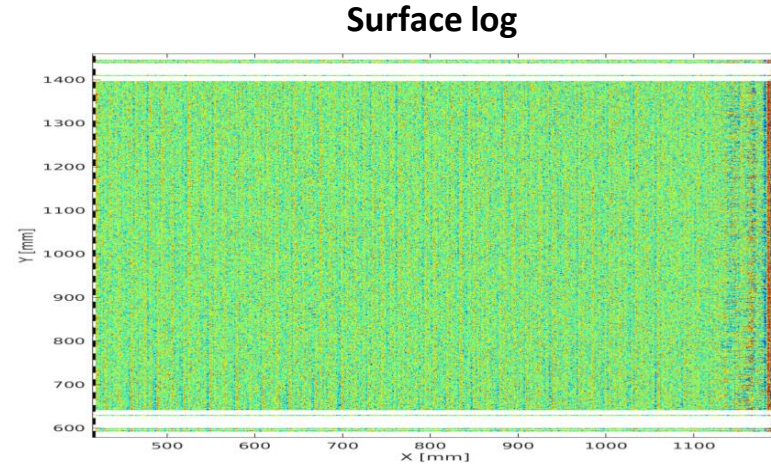
Recipe #4: Servo log anomaly detection for Flat Panel Displays (FPD)

Credit fraud detection uses deep learning

DL technique used: Deep anomaly detection (unsupervised learning)



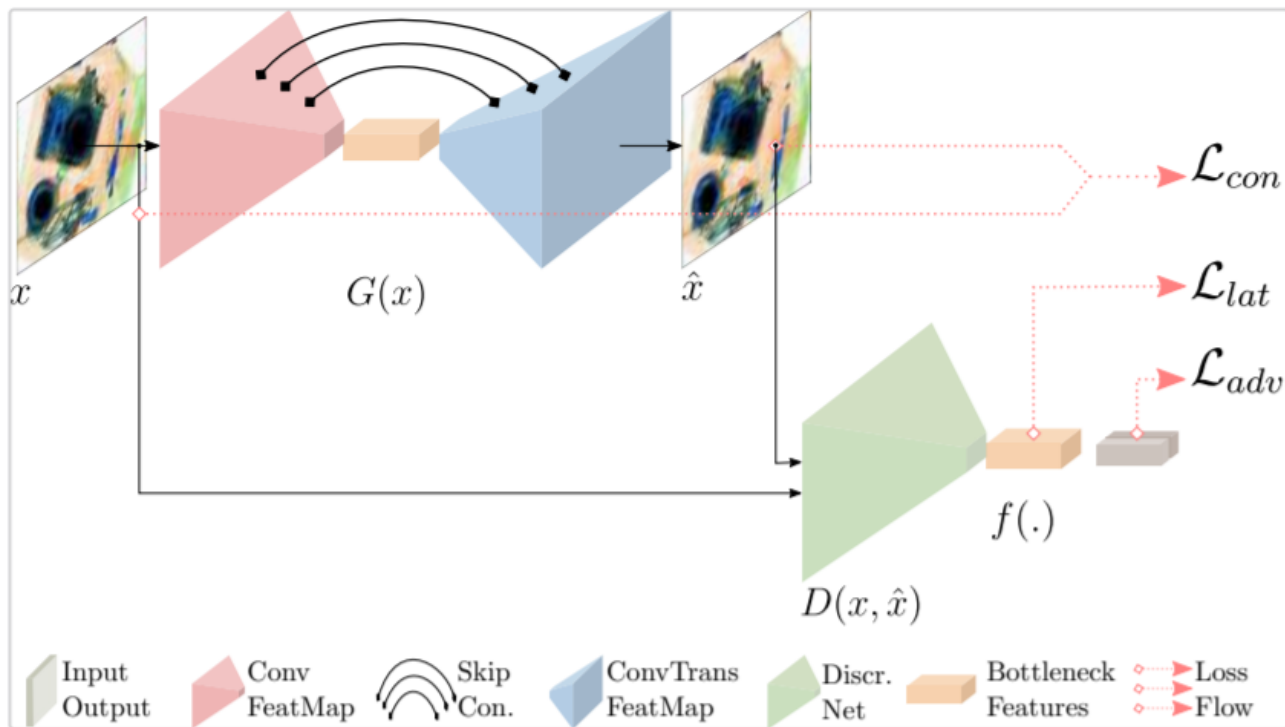
“Muras*” are unwanted defects in FPD mask writing



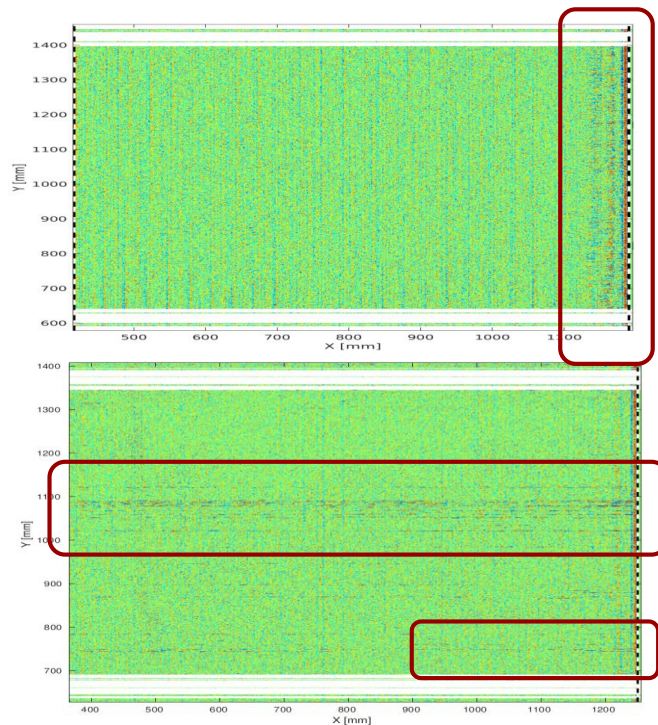
Servo parameter logs record values for every x,y position of plate
Surface log is used to identify “Muras”

*Mura means irregularity in Japanese

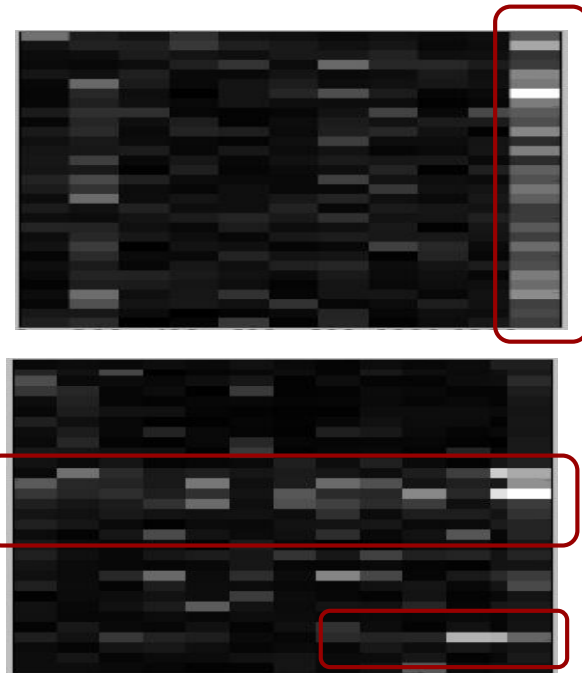
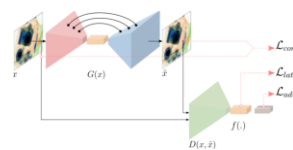
Anomaly detection use Generative Adversarial Networks (GAN)



“Muras” can be identified by unsupervised DL



Deep Anomaly Detection



Bright regions are anomalies

A background graphic featuring a complex network of white dots connected by thin white lines, resembling a neural network or a data mesh. This network is set against a gradient background that transitions from a teal color on the left to a bright green on the right. A large, semi-transparent green circle is centered in the upper half of the image, containing the text for the Center for Deep Learning in Electronics Manufacturing.

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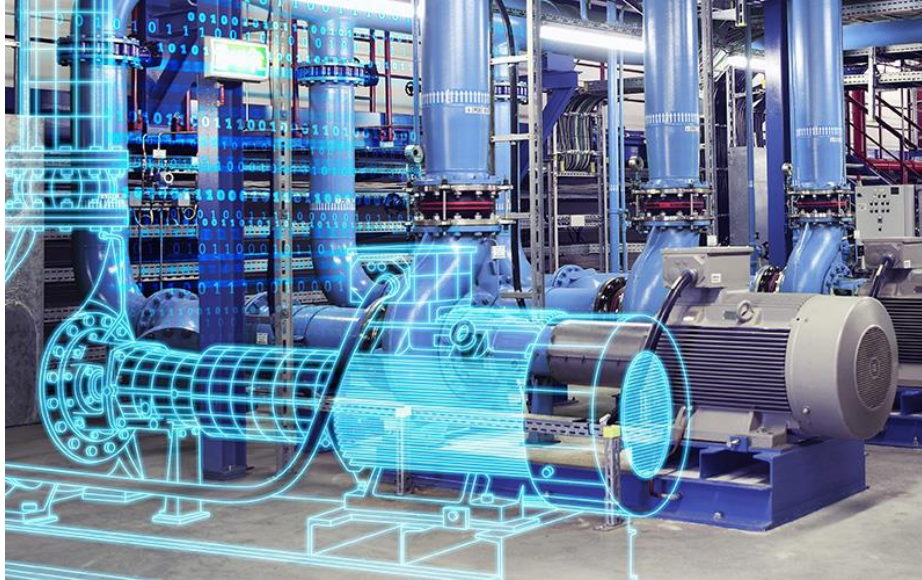
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Recipe #5: Digital twins creation

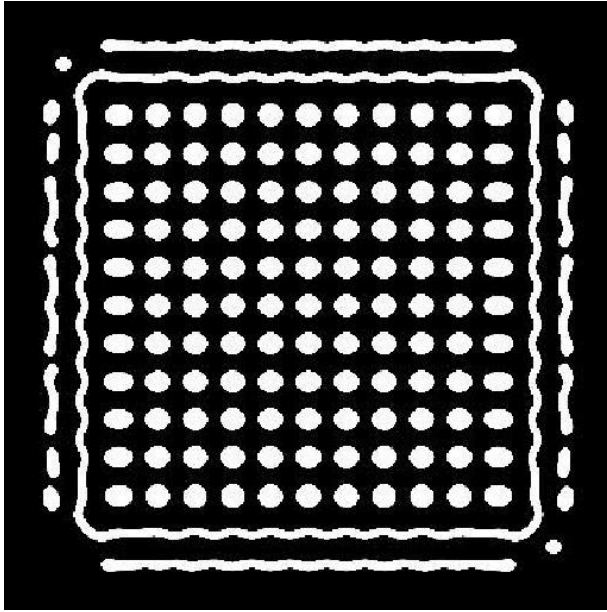
Digital twins can benefit from deep learning

DL technique used: mixture models, GANs (semi-supervised DL)

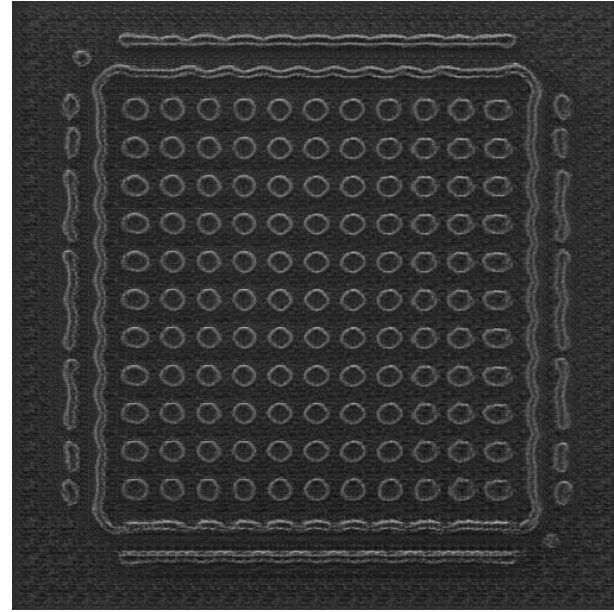


Today's 3 PM talk "Making digital twins using the Deep Learning Kit (DLK)" will cover digital twins in more details

SEM digital twin

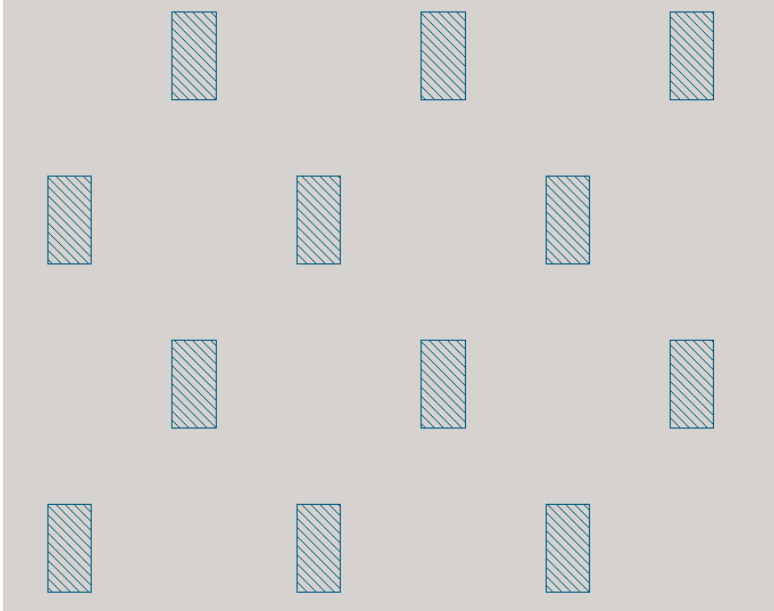


Mask shape



Constructed SEM using
digital twin from CAD data

ILT digital twin

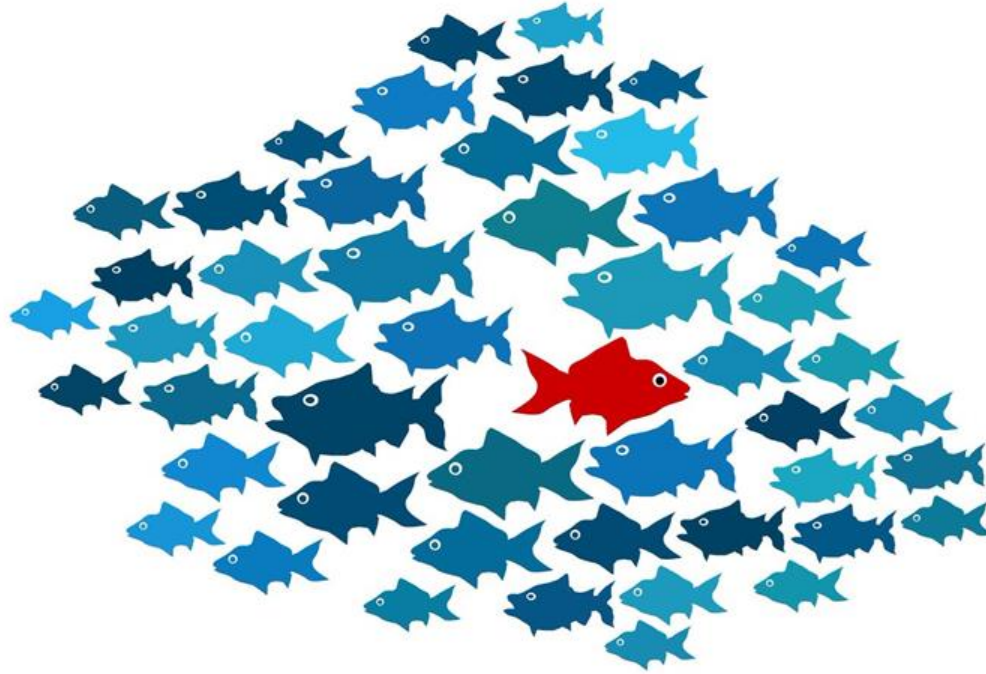


Target wafer



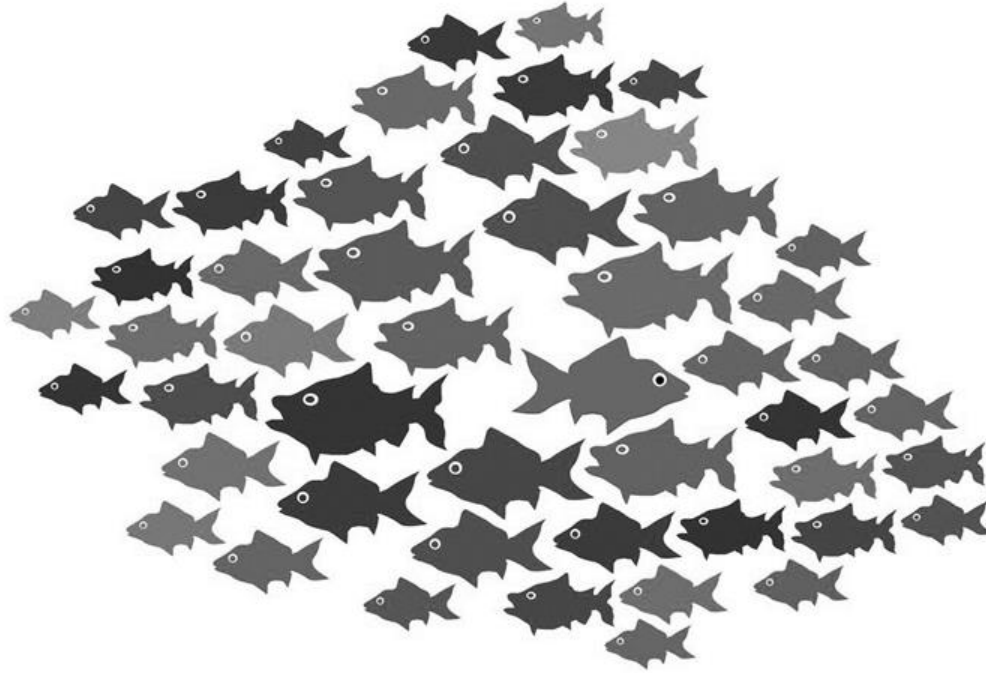
Constructed mask shapes with assist features
using digital twin

Humans can find an anomaly easily



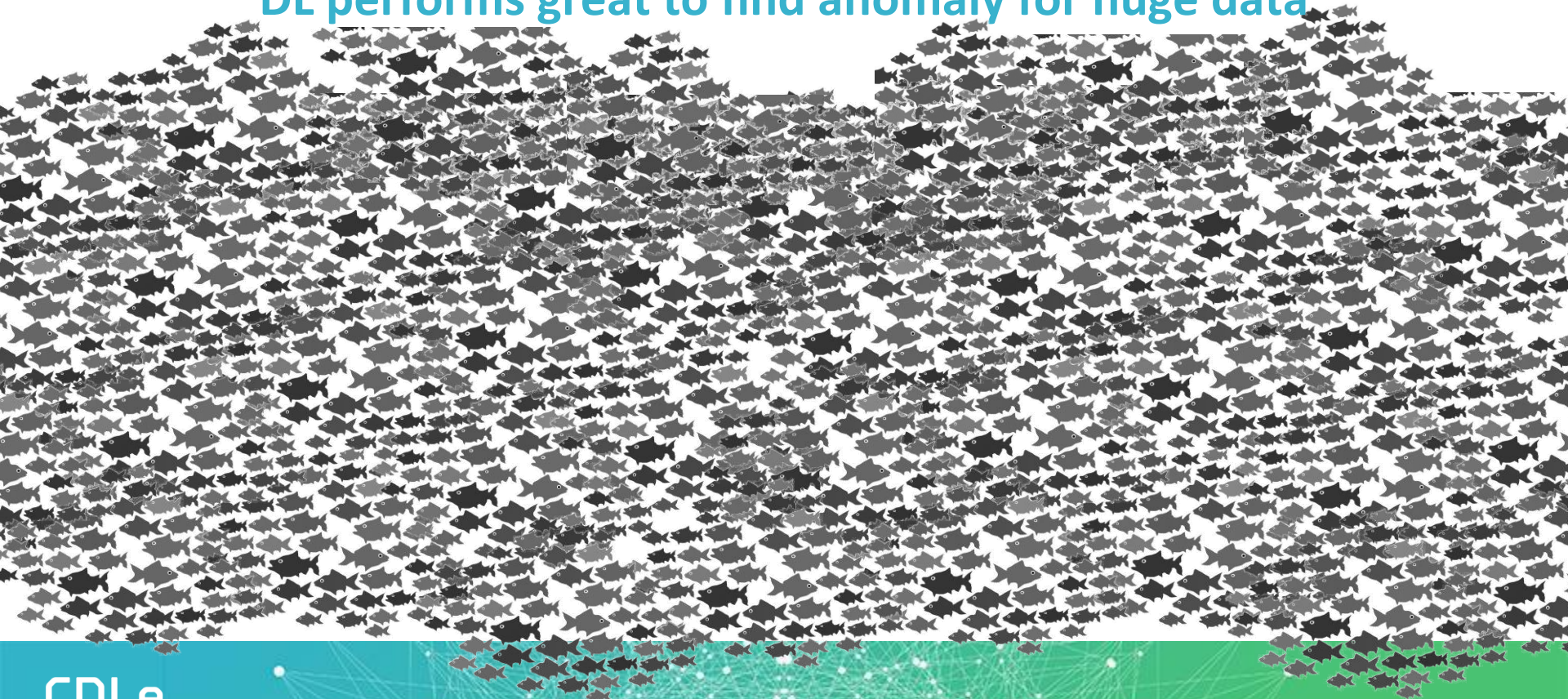
How about now?

Still find anomaly?



And now?

DL performs great to find anomaly for huge data



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